

# OVERVIEW PURGE SOLUTIONS

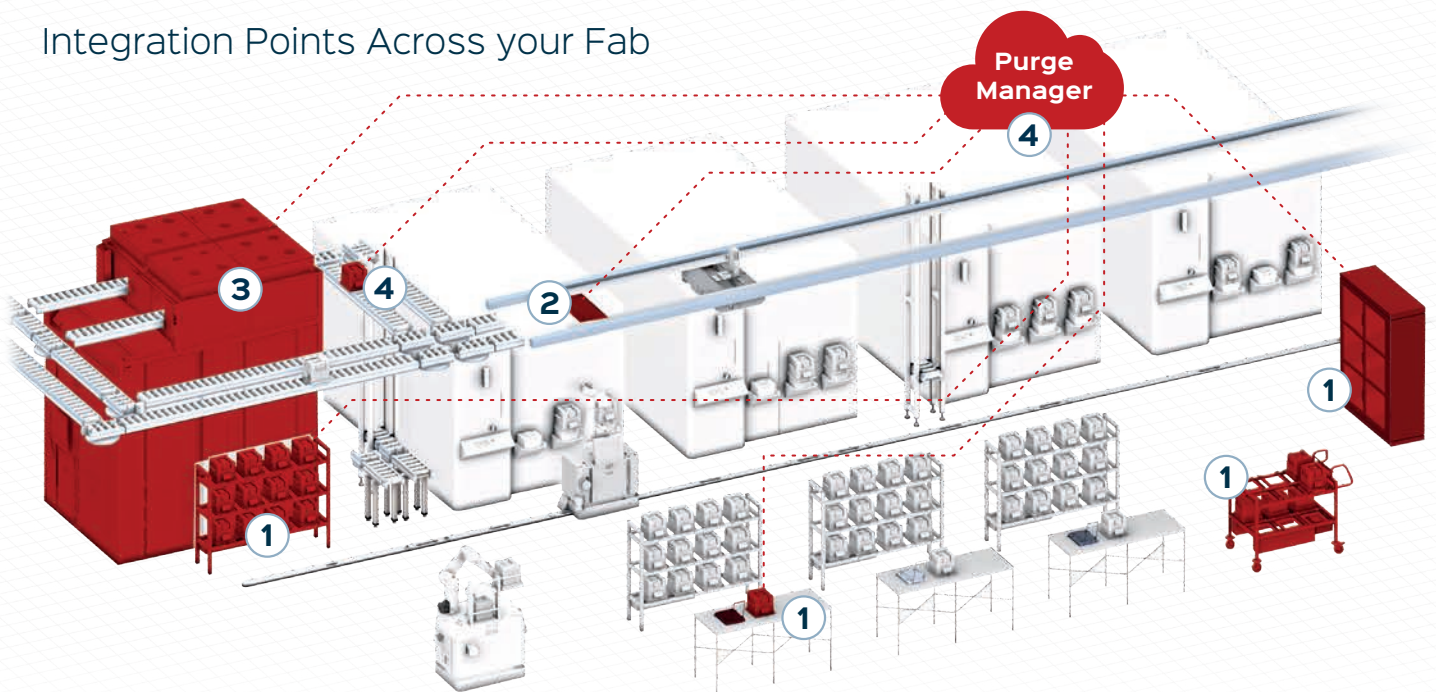
Systems for FOUP & SMIF Pods

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<b>1</b> <b>PURGE Flex</b> Stand-Alone Purge Solutions	<b>2</b> <b>PURGE Sky</b> OHT-Integrated Purge Solutions	<b>3</b> <b>PURGE Ground</b> Floor-Based Purge Solutions	<b>4</b> <b>PURGE Mind</b> Purge Intelligence & Add-ons
<ul style="list-style-type: none"> <li>• Purge cabinet</li> <li>• Purge rack</li> <li>• Purge station</li> <li>• Purge trolley</li> </ul>	<ul style="list-style-type: none"> <li>• Purge system in overhead buffers</li> </ul>	<ul style="list-style-type: none"> <li>• Purge system in stockers &amp; DIE banks</li> </ul>	<ul style="list-style-type: none"> <li>• Purge Manager Software</li> <li>• Qualification FOUP</li> </ul>

## Integration Points Across your Fab



## Protecting Wafers between Process Steps

### The Challenge

#### Why wafers need protection

Between process steps, wafers idle in pods. Exposure to ambient air can cause oxidation, particle contamination, & chemical degradation – risking yield and reliability.

### The Solution

#### Nitrogen Purging of Pods

Dry nitrogen (N<sub>2</sub>) flushes out moisture and contaminants, creating a clean, inert atmosphere inside the Pod (FOUP, SMIF Pod) protecting wafers during storage and transport.

### Key Features

- Permanent process control ensures repeatable performance
- Purging follows customized purge profiles
- Automatic alarm system in case of faults
- Fast purge cycles with low N<sub>2</sub> consumption
- Modular & retrofit-ready
- **NEW: Humidity monitoring**

### Benefits

- Higher wafer yield
- Seamless fab integration
- Scalable & future-proof
- Enhanced process traceability
- More efficiency without additional footprint
- Additional process data for quality assurance